

ヘテロ接合型結晶シリコン太陽電池におけるアモルファスシリコン界面層の物性と発電性能の相関

Effects of a-Si:H bilayers in a-Si:H/c-Si heterojunction solar cells

齋 均¹、許 宏榮²、陳 柏璋²、陳 珮伶²、松井 卓矢¹

¹産業技術総合研究所 ゼロエミッション国際共同研究センター、²台湾交通大学

H. Sai,¹ H.-J. Hsu,² P.-W. Chen,² P.-L. Chen,² T. Matsui¹ (1: GZR, AIST, Japan, 2: NTSU, Taiwan)

Research Background

■ a-Si:H/c-Si heterojunction (SHJ) solar cells

- Excellent surface passivation by using **a-Si:H** [1]
- High efficiency (> 25%), high V_{OC} and low T-coefficient
- Suitable to bi-facial modules
- Applicable to thin wafers thanks to low-T process

■ Key issue – (i)a-Si:H/c-Si interface

□ Surface passivation

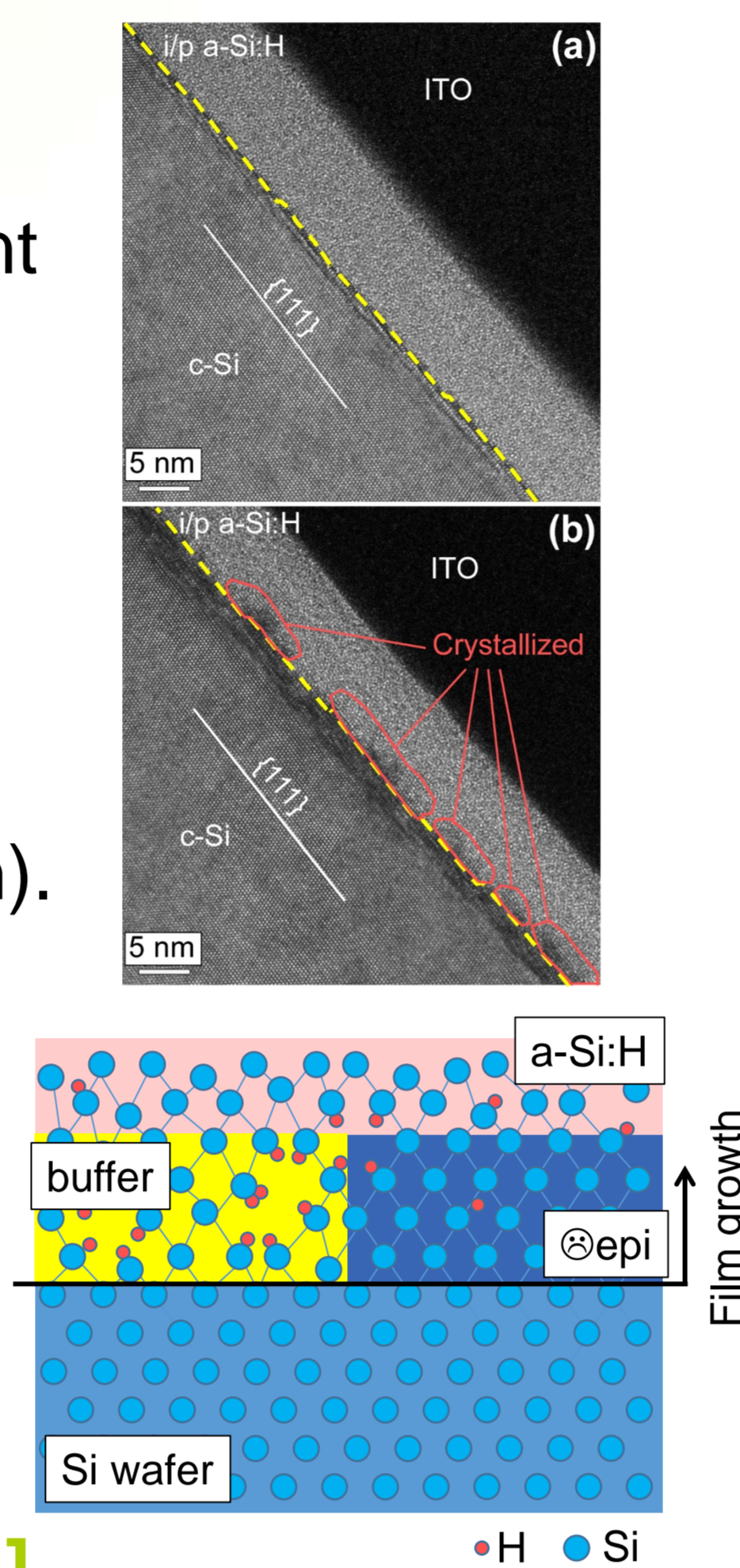
- Abrupt a-Si:H/c-Si interface is preferable. Epitaxial growth is detrimental (either as-grown or post-growth).
- Overlying p-layer deteriorates the passivation

□ Carrier transport channel

- Series resistance should be minimized.

■ 2-step growth of (i)a-Si:H [2-4]

- **Interfacial layer (i_1) + bulk layer (i_2)** is effective for improving surface passivation.
- Record-efficiency (25.1%) cell has been achieved.[4]



Research Objective

■ Our previous study [3] clarified:

- Porous and H-rich a-Si:H layers are suited for the interfacial layer (i_1).
- Such layers are grown with pure SiH_4 plasma at high-pressure and high-power conditions.
- **Microstructure factor R^*** determined by FT-IR is useful to optimize the i_1 -layer.

■ However,

- Material properties of a-Si:H can be tuned by various process (PECVD) parameters.

Objective:

How do the growth parameters affect the R^* of a-Si:H and the photovoltaic performance of SHJ solar cells?

Parameters considered in this work:

- Substrate temperature (T_s)
- Gas pressure (P)
- Precursor gases (SiH_4 and Si_2H_6)

Experimental

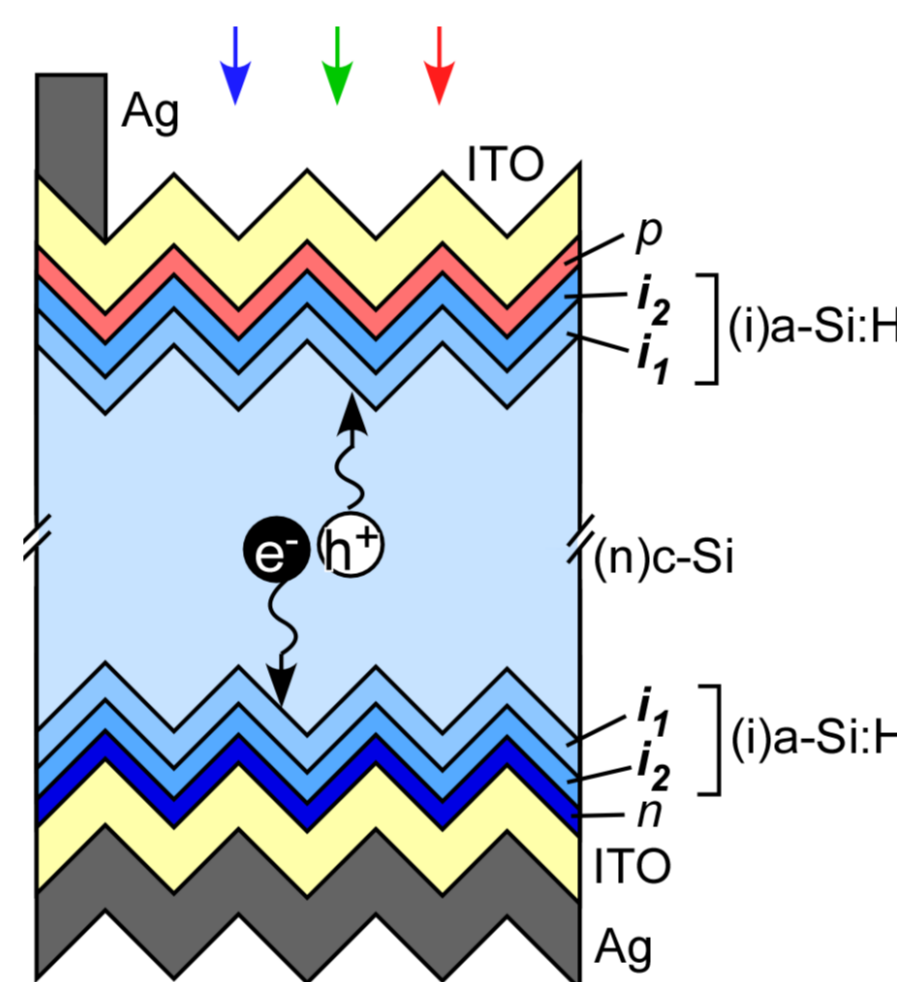
■ Growth of (i)a-Si:H layers

- PECVD, CCP, 13.56MHz
- Characterization: Ellipsometry, FT-IR

Table: Growth conditions for (i)a-Si:H layers

Layer Series	Si_2H_6	i_1	P	i_2
Si precursor	SiH_4 , Si_2H_6	SiH_4	SiH_4	SiH_4
Si_2H_6 concentration, $C_{\text{Si}_2\text{H}_6}$ [Si_2H_6]/([SiH_4]+[Si_2H_6])	0 – 75%	0	0	0
Hydrogen dilution [H_2]/[SiH_4]	0	0	0	10
Substrate temperature, T_s (°C)	200	30 – 400	200	200
Pressure, P (Pa)	13, 40	13	13-40	13
Power density (mW cm^{-2})	11	11	11	11

■ Solar cell

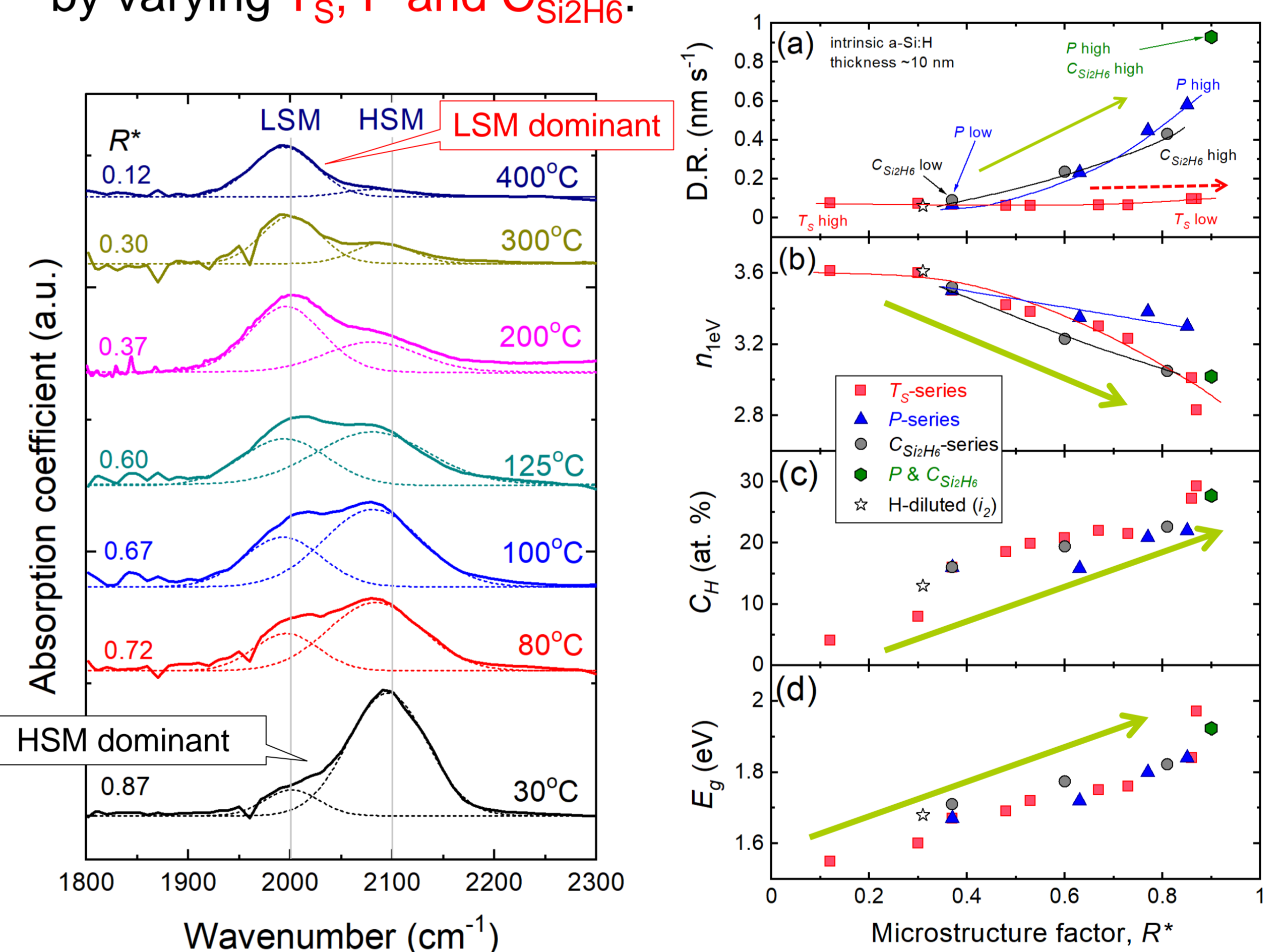


- Front emitter
- (n)FZ-Si, 270 μm
- Pyramid texture
- **(i)a-Si:H bilayer**
- ITO/Ag by SP

Properties of (i)a-Si:H for interfacial layer [6]

■ Microstructure factor [5]: $R^* = I_{HSM} / (I_{LSM} + I_{HSM})$

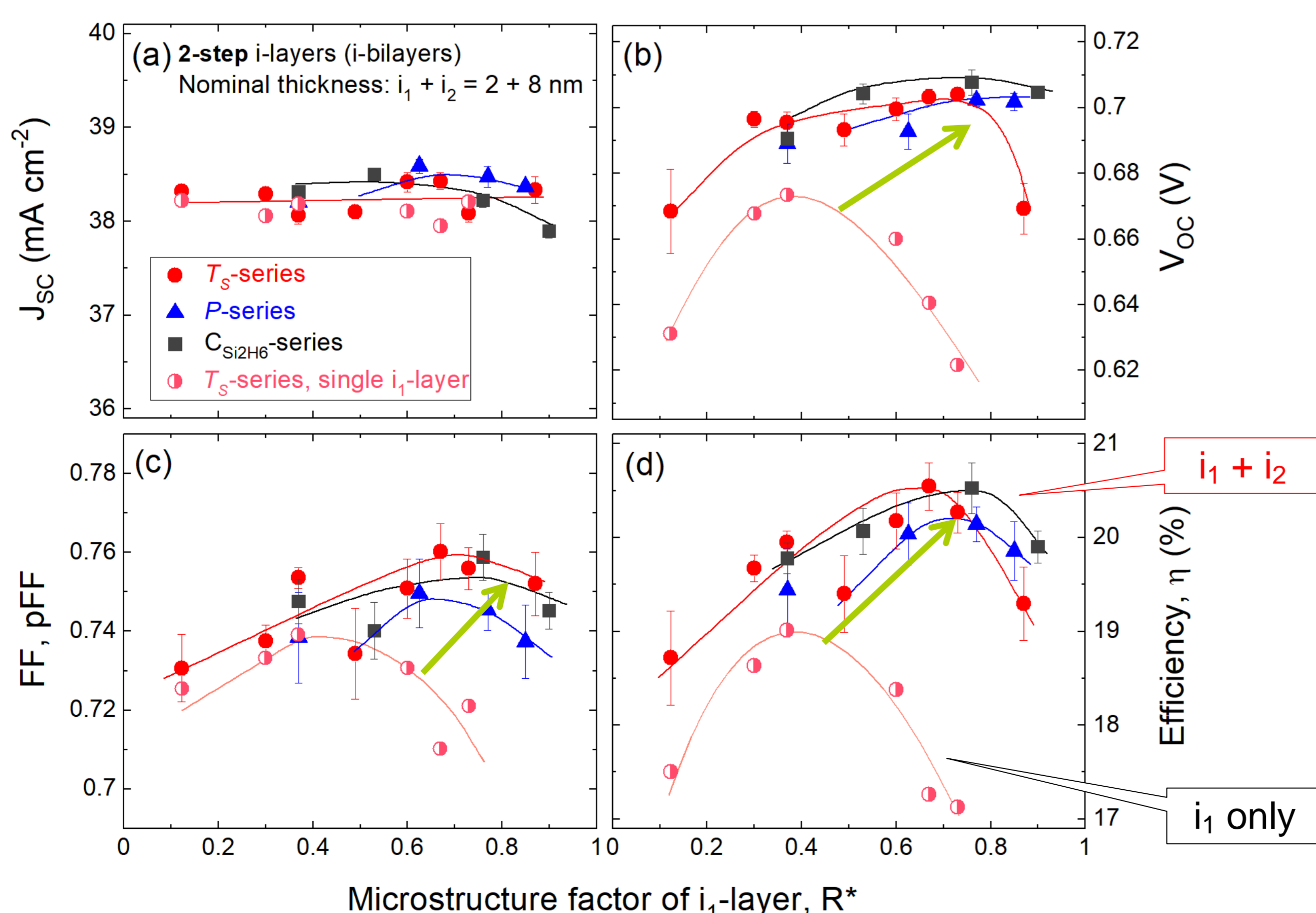
- D.R., refractive index ($n_{1\text{eV}}$), hydrogen content (C_H), and bandgap energy (E_g) as well as R^* are controlled widely by varying T_s , P and $C_{\text{Si}_2\text{H}_6}$.



SHJ cells with (i)a-Si:H bilayers ($i_1 + i_2$) [6]

■ Effect of (i)a-Si:H bilayer: i_1 - and i_2 -layers (2 + 8 nm)

- The V_{OC} , FF, and efficiency are significantly improved by applying i-bilayers.
- The best efficiency is obtained by using i_1 layer with $R^* \sim 0.7$, **regardless of the process conditions.**



Conclusions

- Material properties of a-Si:H layers can be tuned widely by controlling various PECVD parameters: temperature, pressure, mixing of SiH_4 and Si_2H_6 etc.
- Microstructure factor R^* of interfacial a-Si:H layers is a good measure to improve the surface passivation at a-Si:H/c-Si, regardless of the PECVD parameters.

Acknowledgement

T. Oku, Y. Sato, and M. Tanabe in AIST for their technical supports.

References

- [1] S. De Wolf., Green, 2, 7-24 (2012).
- [2] W. Liu *et al.*, J. Appl. Phys. 120, 175301 (2016).
- [3] H. Sai *et al.*, J. Appl. Phys. 124, 103102 (2018)
- [4] X. Ru *et al.*, Sol. Energy Mater. Sol. Cells 215, 110643 (2020)
- [5] J. Müllerová *et al.*, Appl. Surf. Sci. 254, 3690 (2008).
- [6] H. Sai *et al.*, Phys. Status. Solid. A. under review (2021).